Microscopes

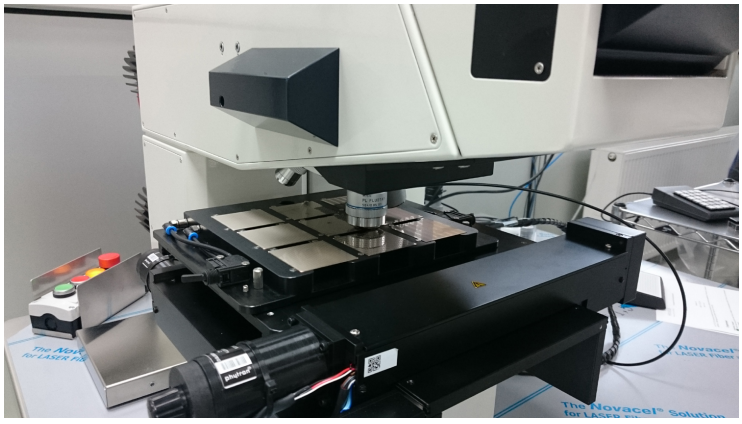
INM200

The software-controlled high-performance microscope:

- Rapid and high-precision laser autofocus
- Motoric 6-fold objective turret
- Motor-controlled screens
- Incident light axis for bright field, dark field, interference contrasting and polarization
- Infrared and visible transmitted light, polarization optional
- Motor-driven Z-stroke 30 mm, step resolution of 18 nm

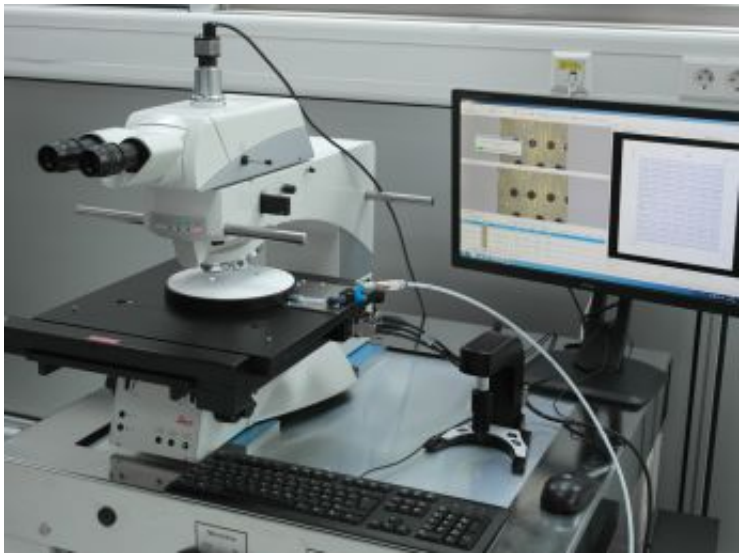
Options:

- Multi-camera port for mono, colour, infrared cameras
- White-light interference
- Confocal module
- Precise scanning stages
- Fiber-coupled spectrometer



INM200 with multi-substrate holder

DM8000 IS



Configuration of the Leica DM8000 by using the Promicron MCS software for semi-automatic wafer amd MEMS Inspection.

Options:

- Infrared incident and transmitted light, applicable for spectral range VIS and NIR
- Front to back side alignment (top/bottom alignment) on Si-wafer through silicon inspection
- MCS Software Suite for inspection, review and a wide range of measurement tasks like line widths, overlay, layer thickness, edge heights and surface profiles
- Scanning stages for ultra-fast Scanning on the Fly
- White-light interferometry

IRUVIS Multispectral Microscope

Measurement and inspection microscope with multispectral configuration. The INM200 convinces with highest optical performance, fast and simple operation and ergonomics for fatigue-free working for hours.

Leica HC Optics stands for highest optical performance in visualization of the smallest structures:

- Objective magnifications from 1.6x to 250x are possible
- Concentration on the essentials - inspektion task - and access to many contrasting techniques (HF, DF, ICR, FL & confocal contrast)
- Optimized and automatic setting of aperture diaphragm
- Maximum reduction of pollution (cleanroom class 1)
- Ideal ergonomics and maximum operating comfort

Customized Microscope Systems

Systems according to customer requirements:

Our own engineering and production possibilities enable us to realize sophisticated systems for high-resolution measurement and inspection. Therefore, we use for example the microscope INM200 as a basis - it convinces with top posibilities in terms of automation and high definition:

- 6" and 8" scanning stages for precise and automatic program execution
- Measurement sensor for high-precision and non-contact Z-measurement
- White light confocal module for thin optical cuts
- White-light interferometry (WLI)
- Software for inspection and measurement
- Software for application-specific tasks

Enquiry